

VE320 Intro to Semiconductor Devices

Summer 2022 — Problem Set 7

July 24, 2022



Exercise 7.1

(a) A Schottky barrier diode formed on n-type silicon has a doping concentration of $N_d = 5 \times 10^{15} \text{ cm}^{-3}$ and a barrier height of $\phi_{B0} = 0.65 \text{ V}$. Determine the builtin potential barrier V_{bi} .

(b) If the doping concentration changes to $N_d = 10^{16} \text{ cm}^{-3}$, determine the values of ϕ_{B0} and V_{bi} . Do these values increase, decrease, or remain the same?

(c) Repeat part (b) if the doping concentration is $N_d = 10^{15} \text{ cm}^{-3}$.

Answer:

(a)

$$\begin{aligned} V_{bi} &= \phi_{B0} - \phi_n \\ \phi_n &= V_t \ln \left(\frac{N_c}{N_d} \right) \\ &= (0.0259) \ln \left(\frac{2.8 \times 10^{19}}{5 \times 10^{15}} \right) \\ &= 0.2235 \text{ V} \\ V_{bi} &= 0.65 - 0.2235 = 0.4265 \text{ V} \end{aligned}$$

(b)

$$\begin{aligned} \phi_n &= (0.0259) \ln \left(\frac{2.8 \times 10^{19}}{10^{16}} \right) \\ &= 0.2056 \text{ V} \\ V_{bi} &= 0.65 - 0.2056 = 0.4444 \text{ V} \end{aligned}$$

V_{bi} increases, ϕ_{B0} remains constant

(c)

$$\begin{aligned} \phi_n &= (0.0259) \ln \left(\frac{2.8 \times 10^{19}}{10^{15}} \right) \\ &= 0.2652 \text{ V} \\ V_{bi} &= 0.65 - 0.2652 = 0.3848 \text{ V} \end{aligned}$$

V_{bi} decreases, ϕ_{B0} remains constant

Exercise 7.2

For a p type semiconductor in contact with a metal, when does it form a Schottky contact, and when does it form an Ohmic contact? Please draw the energy band diagram for each case, and explain using your own words

Answer:

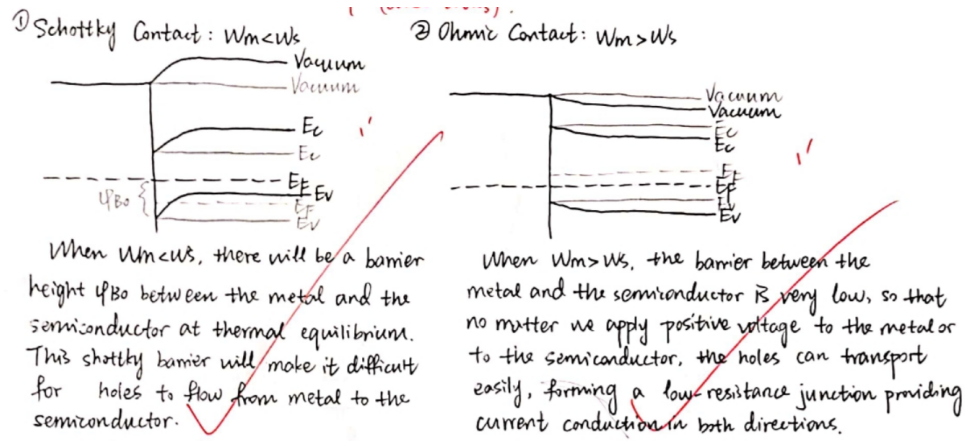


Figure 1: Figure for Problem 7.2

Exercise 7.3

A pn junction diode and a Schottky diode each have cross-sectional areas of $A = 8 \times 10^{-4} \text{ cm}^2$. The reverse saturation current densities at $T = 300 \text{ K}$ for the pn junction diode and Schottky diode are $8 \times 10^{-13} \text{ A/cm}^2$ and $6 \times 10^{-9} \text{ A/cm}^2$, respectively. Determine the required forward-bias voltage in each diode to yields currents of

- (a) $150 \mu\text{A}$
- (b) $700 \mu\text{A}$
- (c) 1.2 mA

Answer:

For the pn junction,

$$I_s = (8 \times 10^{-4}) (8 \times 10^{-13}) = 6.4 \times 10^{-16} \text{ A}$$

(a)

$$\begin{aligned} V_a &= (0.0259) \ln \left(\frac{150 \times 10^{-6}}{6.4 \times 10^{-16}} \right) \\ &= 0.678 \text{ V} \end{aligned}$$

(b)

$$\begin{aligned} V_a &= (0.0259) \ln \left(\frac{700 \times 10^{-6}}{6.4 \times 10^{-16}} \right) \\ &= 0.718 \text{ V} \end{aligned}$$

(c)

$$\begin{aligned} V_a &= (0.0259) \ln \left(\frac{1.2 \times 10^{-3}}{6.4 \times 10^{-16}} \right) \\ &= 0.732 \text{ V} \end{aligned}$$

For the Schottky junction,

$$I_{sT} = (8 \times 10^{-4}) (6 \times 10^{-9}) = 4.8 \times 10^{-12} \text{ A}$$

- (a) $V_a = (0.0259) \ln \left(\frac{150 \times 10^{-6}}{4.8 \times 10^{-12}} \right) = 0.447 \text{ V}$
- (b) $V_a = (0.0259) \ln \left(\frac{700 \times 10^{-6}}{4.8 \times 10^{-12}} \right) = 0.487 \text{ V}$
- (c) $V_a = (0.0259) \ln \left(\frac{1.2 \times 10^{-3}}{4.8 \times 10^{-12}} \right) = 0.501 \text{ V}$

Exercise 7.4

A metal, with a work function $\phi_m = 4.2$ V, is deposited on an n-type silicon semiconductor with $\chi_s = 4.0$ V and $E_g = 1.12$ eV. Assume no interface states exist at the junction. Let $T = 300$ K.

(a) Sketch the energy-band diagram for zero bias for the case when no space charge region exists at the junction.

(b) Determine N_d so that the condition in part (a) is satisfied.

(c) What is the potential barrier height seen by electrons in the metal moving into the semiconductor?

Answer:

(a) Plot

(b) We need $\phi_n = \phi_m - \chi = 4.2 - 4.0 = 0.20$ V And

$$\phi_n = V_t \ln \left(\frac{N_c}{N_d} \right)$$

or

$$0.20 = (0.0259) \ln \left(\frac{2.8 \times 10^{19}}{N_d} \right)$$

which yields

$$N_d = 1.24 \times 10^{16} \text{ cm}^{-3}$$

(c)

Barrier height = 0.20 V

Exercise 7.5

A metal-semiconductor junction is formed between a metal with a work function of 4.3 eV and p-type silicon with an electron affinity of 4.0 eV. The acceptor doping concentration in the silicon is $N_a = 5 \times 10^{16} \text{ cm}^{-3}$. Assume $T = 300$ K.

(a) Sketch the thermal equilibrium energy-band diagram.

(b) Determine the height of the Schottky barrier.

(c) Sketch the energy-band diagram with an applied reverse-biased voltage of $V_R = 3$ V.

(d) Sketch the energy-band diagram with an applied forward-bias voltage of $V_a = 0.25$ V

Answer:

Plot

Exercise 7.6

The dc charge distributions of four ideal MOS capacitors are shown in Figure P10.1. For each case:

(a) Is the semiconductor n or p type?

(b) Is the device biased in the accumulation, depletion, or inversion mode?

(c) Draw the energyband diagram in the semiconductor region.

Answer:

(a) p-type; inversion

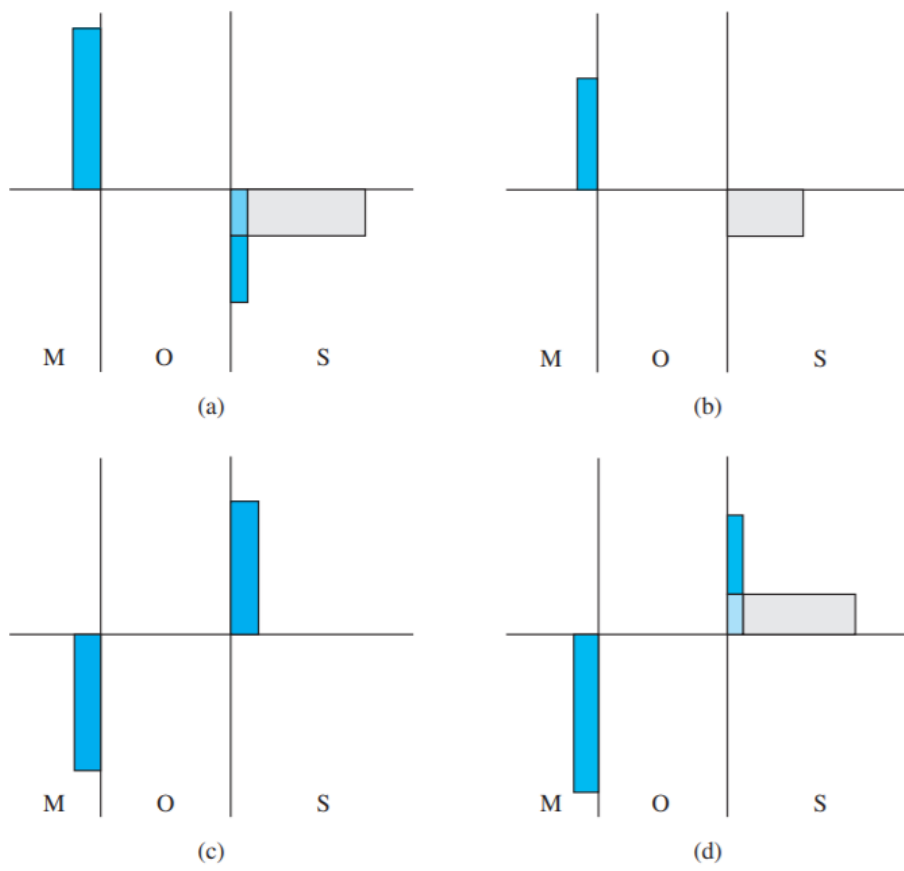


Figure 2: Figure for Problem 7.6

- (b) p-type; depletion
- (c) p-type; accumulation
- (d) n-type; inversion

Exercise 7.7

- (a) Consider an n⁺polysilicon-silicon dioxide-n-type silicon MOS structure. Let $N_d = 4 \times 10^{15} \text{ cm}^{-3}$. Calculate the ideal flat-band voltage for $t_{ox} = 20 \text{ nm} = 200 \text{ \AA}$
- (b) Considering the results of part (a), determine the shift in flat-band voltage for (i) $Q'_{ss} = 4 \times 10^{10} \text{ cm}^{-2}$ and (ii) $Q'_{ss} = 10^{11} \text{ cm}^{-2}$.
- (c) Repeat parts (a) and (b) for an oxide thickness of $t_{ox} = 12 \text{ nm} = 120 \text{ \AA}$.

Answer:

- (a) $\phi_{ms} \cong -0.42 \text{ V}$ $V_{FB} = \phi_{ms} = -0.42 \text{ V}$
- (b) $C_{ox} = \frac{(3.9)(8.85 \times 10^{-14})}{200 \times 10^{-8}} = 1.726 \times 10^{-7} \text{ F/cm}^2$
- (i) $\Delta V_{FB} = -\frac{Q'_{ss}}{C_{ox}} = -\frac{(4 \times 10^{10})(1.6 \times 10^{-19})}{1.726 \times 10^{-7}} = -0.0371 \text{ V}$
- (ii) $\Delta V_{FB} = -\frac{(10^{11})(1.6 \times 10^{-19})}{1.726 \times 10^{-7}} = -0.0927 \text{ V}$
- (c) $V_{FB} = \phi_{ms} = -0.42 \text{ V}$ $C_{ox} = \frac{(3.9)(8.85 \times 10^{-14})}{120 \times 10^{-8}} = 2.876 \times 10^{-7} \text{ F/cm}^2$
- (i) $\Delta V_{FB} = -\frac{(4 \times 10^{10})(1.6 \times 10^{-19})}{2.876 \times 10^{-7}} = -0.0223 \text{ V}$
- (ii) $\Delta V_{FB} = -\frac{(10^{11})(1.6 \times 10^{-19})}{2.876 \times 10^{-7}} = -0.0556 \text{ V}$

Exercise 7.8

Consider an n⁺polysilicon gate on silicon dioxide with a p-type silicon substrate doped to $N_a = 3 \times 10^{16} \text{ cm}^{-3}$. Assume $Q'_{ss} = 5 \times 10^{10} \text{ cm}^{-2}$. Determine the required oxide thickness such that the threshold voltage is $V_{TN} = +0.65 \text{ V}$. Please provide the process of derivation.

Answer:

$$\Phi_{tp} = V_t \ln \left(\frac{N_a}{n_i} \right) = (0.0259) \ln \left(\frac{3 \times 10^{16}}{1.5 \times 10^{10}} \right) = 0.376 \text{ V}$$

$$X_{d\tau} = \left\{ \frac{4 \in s\phi_{fp}}{dV_a} \right\}^{\frac{1}{2}} = \left\{ \frac{4 \times 11.7 \times 8.85 \times 10^{-14} \times 0.376}{1.6 \times 10^{-19} \times 3 \times 10^{16}} \right\}^{\frac{1}{2}} = 1.8 \times 10^{-5} \text{ cm}$$

$$|Q'_{sp}(\max)| = eN_a x_{dT} = 1.6 \times 10^{-19} \times 3 \times 10^6 \times 1.8 \times 10^{-5} = 8.646 \times 10^{-8} \text{ C/cm}^2$$

$$\text{We have } V_{TN} = (|Q'_{sd \max}| - Q'_{ss}) \left(\frac{t_{ox}}{\epsilon_{ox}} \right) + \phi_{ms} + 2\phi_{fp} \Rightarrow t_{ox} = 4.5 \times 10^{-6} \text{ cm}$$

Exercise 7.9

Draw the C-V curves of a MOS capacitor with n-type Si as the substrate, at low frequency and high frequency, respectively. Explain why they are different.

Answer:

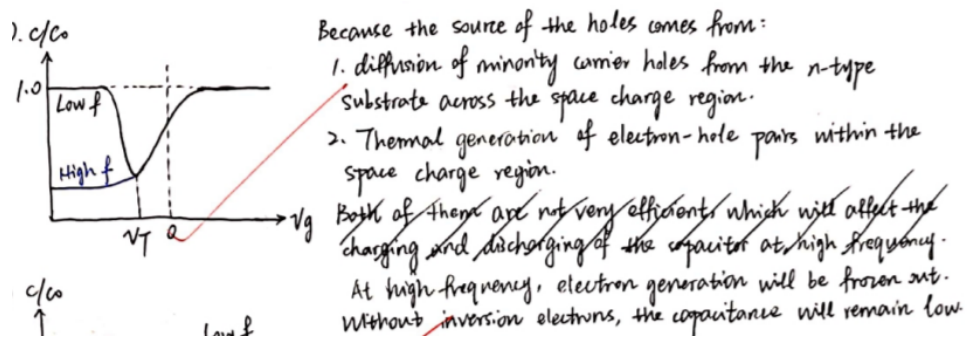


Figure 3: Figure for Problem 7.9

Reference

1. Neamen, Donald A. Semiconductor physics and devices: basic principles. McGraw-hill, 2003.